

Notice of References Cited	Application/Control No.	Applicant(s)/Patent Under Reexamination	
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Examiner	Art Unit	3729	Page 1 of 1
Dexter Tugbang			

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	C	US-			
	D	US-			
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	M	US-			

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	V	Ilyefalvi et al, "Application of Laser Engraving for the Fabrication of Fine Resolution Printed Wiring Laminates for MCM-Ls", Electronic Components and Technology Conference, May 1997, pages 507-510.
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)

Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.